

PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER 1756**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Masaaki KURIHARA et al.

Group Art Unit: 1756

Application No.: 10/614,345

Examiner: J. RUGGLES

Filed: July 8, 2003

Docket No.: 123770

For: PHASE MASK FOR FORMING DIFFRACTION GRATING, METHOD OF
FABRICATING PHASE MASK AND METHOD OF FORMING DIFFRACTION
GRATING

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the May 30, 2006, Office Action, please consider the following:

Amendments to the Specification;

Amendments to the Claims as reflected in the listing of claims; and

Remarks.